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## Chemical replenishing system CFD-1T-B

### Resolution improvement up to 1.0mL/shot offers finer flow adjustment

#### Resolution improvement

The resolution of the CFD-1T-B has been greatly improved compared to our existing models. The minimum flow of 1mL/shot offers greater accuracy in chemical condensation control that is required in the wafer cleaning process. The CFD-1T-B always feeds the correct quantity of chemical without overshoot, eliminating excess liquid wastage. In addition, the anti-siphon mechanism prevents unintentional siphoning.

#### Corrosion resistant wet ends

Fluoroplastic wet ends (PTFE, PFA, PCTFE) is capable of handling the strong acids, alkalines and hydrogen peroxide required for semiconductor processing. PTFE, PFA, PP, PVC external parts and PTFE coated screws provide additional protection against chemical attack.

#### Flow rate adjustment

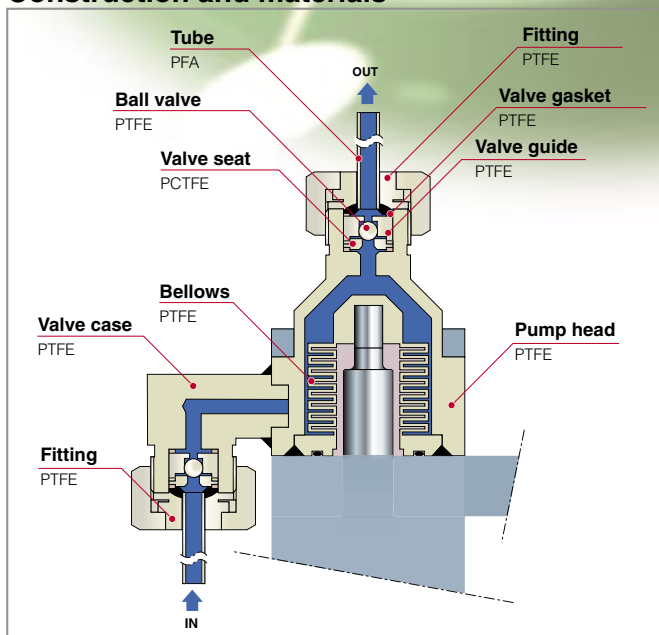
Simply open the bottom cover to easily adjust stroke length to give between 1.0-2.7ml/shot. (Factory default is 1.0ml/shot)

#### Leak sensor

Every unit is equipped with a leakage sensor to detect any leakage immediately.



### Construction and materials



### Specifications

Pump specification	Application	Chemical replenishing
	Discharge capacity	1mL/shot
	Max. discharge pressure	0.05MPa
	Liquid temperature range	20 - 60°C
	Max. stroke speed	30spm
	Max. supply air pressure	0.15 - 0.3MPa
	Max. air consumption	2.5NL/min
	Wet end materials	PTFE, PFA, PCTFE
	Liquid port bore	1/4" PFA tube (6.35x4.35)
	Supply air port bore	Rc1/8
Photosensor specification	Weight	1.1kg
	Model	Transmission type micro photo sensor
	Power voltage	5 - 24V DC ±10%
	Output mode	NPN transistor open collector
	Allowable current	50mA or below
	Cord	5m PVC four-core cable (Outer dia. 5.2mm) with 0.5 - round terminal

### Wafer wet-bench

